IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

pplicant(s):

ERAN DVIR, MOSHE FINAROV, ELI HAIMOVICH,

BENJAMIN SHULMAN

90 Assignee:

Nova Measuring Instruments, Ltd.

"APPARATUS FOR OPTICAL INSPECTION OF WAFERS

DURING POLISHING"

Serial No.:

08/497,382

Filing Date: June 29, 1995

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Examiner:

E. Morgan

Art Unit: 3203

Attorney Docket No.: M-3417-US

San Jose, California December 30, 1996

COMMISSIONER OF PATENTS AND TRADEMARKS Washington, D. C. 20231

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

REMARKS

This paper is in response to the paper dated October 2, 1996. In that paper the Examiner issued a restriction to one of the following inventions under 35 U.S.C. §121:

- Claims 1-10, 13-16, drawn to measuring the thickness of a wafer, classified in class 451, subclass 6.
- II. Claims 11, 12, drawn to a method of placing a wafer in water, classified in class 437, subclass 984.

Applicants hereby elect Group I, Claims 1-10, 13-16 for examination. If the Examiner has any questions concerning this paper, the Examiner is respectfully requested to telephone Applicants' attorney at the number given below.

Respectfully submitted,

Forrest E. Gunnison

Attorney for Applicant(s) Reg. No. 32,899 (408) 453-9200

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner of Petents and Trademarks, Washington, D.C., 20231, on December 30, 1996.

Da 30, 1996

Date of Signature

Attorney for Applicant(s)

SER. NO. 08/497,382

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